

## WHAT IS CLAIMED IS:

1. A microactuator device having a cut face formed by cutting, wherein said cut face is subjected to anti-release treatment for preventing release of particles produced by cutting.

2. A microactuator device according to claim 1, wherein said anti-release treatment is carried out by baking an entire surface of said microactuator device including said cut face to form a sintered image after cutting into a final product shape.

3. A microactuator device according to claim 1, wherein said anti-release treatment is carried out by polishing an entire surface of said microactuator device including said cut face formed by cutting after baking.

4. A microactuator device according to claim 1, wherein said anti-release treatment is carried out by reheating an entire surface of said microactuator device including said cut face formed by cutting after baking to thereby re-fix said particles to said entire surface.

5. A microactuator device according to claim 1, wherein said anti-release treatment is carried out by exclusively heating said cut face formed by cutting after baking to thereby re-fix said particles to said cut face.

6. A microactuator device according to claim 2, wherein said anti-release treatment is followed by washing of an entire surface of said microactuator device including said cut face to remove said particles.

7. A microactuator device according to claim 3, wherein said anti-release treatment is followed by washing of an entire surface of said microactuator device including said cut face to remove said particles.

8. A microactuator device according to claim 4, wherein said anti-release treatment is followed by washing of an entire surface of said microactuator device including said cut face to remove said particles.

9. A microactuator device according to claim 5, wherein said anti-release treatment is followed by washing of an entire surface of said microactuator device including said cut face to remove said particles.

10. A microactuator device according to claim 1, wherein said anti-release treatment is carried out by coating said cut face formed by cutting after baking with a glass to avoid exposure of said cut face.

11. A microactuator device according to claim 1, wherein said anti-release treatment is carried out by coating an entire surface of said microactuator device including said cut face formed by cutting after baking with a flexible resin material which hardly suppresses the displacement of said microactuator device.

12. A microactuator device according to claim 1, wherein said microactuator device comprises a multilayer structure which includes a plurality of piezoelectric elements and a plurality of internal electrodes alternately laminated and which has said cut face.

13. A microactuator device according to claim 2, wherein said microactuator device comprises a multilayer structure which includes a plurality of piezoelectric elements and a plurality of internal electrodes alternately laminated and which has said cut face.

14. A microactuator device according to claim 3, wherein said microactuator device comprises a multilayer structure which includes a plurality of piezoelectric elements and a plurality of internal electrodes alternately laminated and which has said cut face.

15. A microactuator device according to claim 4, wherein said microactuator device comprises a multilayer structure which includes a plurality of piezoelectric elements and a plurality of internal electrodes alternately laminated and which has said cut face.

16. A microactuator device according to claim 5, wherein said microactuator device comprises a multilayer structure which includes a plurality of piezoelectric elements and a plurality of internal electrodes alternately laminated and which has said cut face.

17. A microactuator device according to claim 7, wherein said microactuator device comprises a multilayer structure which includes a plurality of piezoelectric elements and a plurality of internal electrodes alternately laminated and which has said cut face.

18. A microactuator device according to claim 8, wherein said microactuator device comprises a multilayer structure which includes a plurality of piezoelectric elements and a plurality of internal electrodes alternately laminated and which has said cut face.

19. A microactuator device according to claim 6, wherein said microactuator device comprises a multilayer structure which includes a plurality of piezoelectric elements and a plurality of internal electrodes alternately laminated and which includes said cut face.

20. A microactuator device according to claim 7, wherein said microactuator device comprises a multilayer structure which includes a plurality of piezoelectric elements and a plurality of internal electrodes alternately laminated and which includes said cut face.

21. A microactuator device according to claim 8, wherein said microactuator device comprises a multilayer structure which includes a plurality of piezoelectric elements and a plurality of internal electrodes alternately laminated and which includes said cut face.

22. A microactuator device according to claim 9, wherein said microactuator device comprises a multilayer structure which includes a plurality of piezoelectric elements and a plurality of internal electrodes alternately laminated and which includes said cut face.